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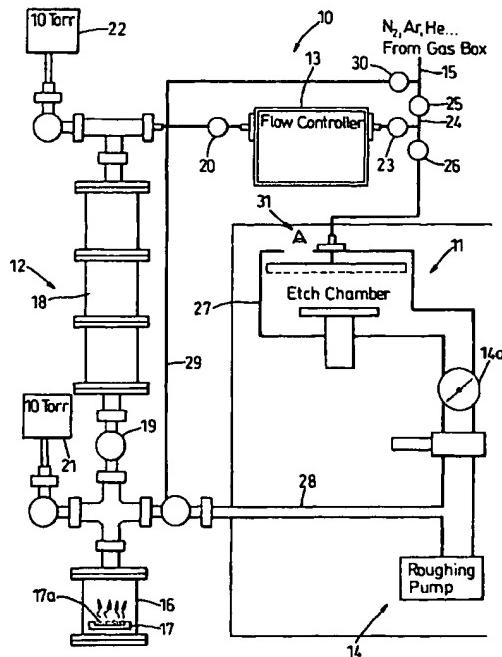
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(54) Method and apparatus for etching a workpiece

(57) An XeF₂ source 12 comprises a XeF₂ source chamber 16, which includes a tray or ampoule 17 for XeF₂ crystals 17a, a reservoir 18 via valve 19, a flow controller 13 fed by the reservoir 18 and a valve 20 be-

tween the reservoir 18 and the controller 13. Pressure sources 21 and 22 are provided respectively to maintain the reservoir 18 and the source chamber 16 at the sublimation pressure of XeF₂. The arrangement allows for a steady supply of XeF₂ to an etching chamber.



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EUROPEAN SEARCH REPORT

Application Number

DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.6)
E	PATENT ABSTRACTS OF JAPAN vol. 1998, no. 13, 30 November 1998 (1998-11-30) & JP 10 209088 A (MITSUBISHI ELECTRIC CORP), 7 August 1998 (1998-08-07) * abstract *	1-3, 6, 8	H01J37/32
A	PATENT ABSTRACTS OF JAPAN vol. 010, no. 325 (E-451), 6 November 1986 (1986-11-06) & JP 61 134019 A (NEC CORP), 21 June 1986 (1986-06-21) * abstract *	1, 6	<p style="text-align: right;">TECHNICAL FIELDS SEARCHED (Int.Cl.6)</p> <p style="text-align: right;">H01J</p>
The present search report has been drawn up for all claims			
Place of search	Date of completion of the search	Examiner	
THE HAGUE	25 November 1999	Schaub, G	
CATEGORY OF CITED DOCUMENTS			
X : particularly relevant if taken alone	T : theory or principle underlying the invention		
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ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.

EP 98 30 3196

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
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Patent document cited in search report	Publication date	Patent family member(s)	Publication date
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JP 61134019 A	21-06-1986	NONE	

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